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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Robert J. SMALL

Application No.: 10/802,780

Art Unit:

Filed: March 18, 2004

Examiner:

For: **RESIDUE REMOVERS FOR
ELECTROHYDRODYNAMIC
CLEANING OF SEMICONDUCTORS**

Atty Docket No.: 060937-0178-US

INFORMATION DISCLOSURE STATEMENT

U.S. Patent and Trademark Office
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Arlington, Virginia 22202

Sir:

In accordance with the duty of disclosure provisions of 37 C.F.R. §1.56, there is hereby provided certain information which the Examiner may consider material to the examination of the subject U.S. patent application. It is requested that the Examiner make this information of record if it is deemed material to the examination of the application.


Enclosed with this Information Disclosure Statement is a list of all patents, publications, applications, or other information submitted for consideration by the Office. There are thirteen (13) references listed in the above-referenced application, only the articles of which are submitted herewith. U.S. references will be provided upon request.

No fee is believed to be due for this submission, since this Information Disclosure Statement is being submitted before the first Office Action. Should any fees be required, however, please charge the required fees to Morgan, Lewis & Bockius LLP Deposit Account No. 50-0310.

Respectfully submitted,

July 30, 2004

By:


Christopher G. Hayden Reg. No. 44,750
MORGAN, LEWIS & BOCKIUS LLP
1111 Pennsylvania Avenue, N.W.
Washington, D.C. 20004
Tel: 202-739-3000
Fax: 202-739-3001

**LIST OF REFERENCES CITED BY APPLICANT**
(Use several sheets if necessary)

ATTY DOCKET NO.

060937-0178

APPLICATION NO

10/802,780

APPLICANT

Robert J. SMALL

FILING DATE

march 18, 2004

GROUP

U.S. PATENT DOCUMENTS

| *EXAMINER INITIAL | | DOCUMENT NUMBER | DATE | NAME | CLASS | SUBCLASS | FILING DATE IF APPROPRIATE |
|----------------------|-----|-----------------|---------|----------------|-------|----------|-------------------------------|
| | A01 | 3,848,258 | 11/1974 | Mahoney et al. | | | |
| | A02 | 3,893,131 | 07/1975 | Perel et al. | | | |
| | A03 | 4,124,801 | 11/1978 | Cook et al. | | | |
| | A04 | 4,264,641 | 04/1981 | Mahoney et al. | | | |
| | A05 | 4,318,028 | 03/1982 | Perel et al. | | | |
| | A06 | 4,462,806 | 07/1984 | Mahoney et al. | | | |
| | A07 | 4,762,975 | 08/1988 | Mahoney et al. | | | |
| | A08 | 4,835,383 | 05/1989 | Mahoney et al. | | | |
| | A09 | 4,896,035 | 01/1990 | Mahoney et al. | | | |
| | A10 | | | | | | |

FOREIGN PATENT DOCUMENTS

| | | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | TRANSLATION | |
|--|-----|-----------------|------|---------|-------|----------|-------------|----|
| | | | | | | | YES | NO |
| | B01 | | | | | | | |
| | B02 | | | | | | | |
| | B03 | | | | | | | |

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

| | | |
|--|-----|---|
| | C01 | Journal of Vacuum Science & Technology B, "Dry Surface Cleaning Using CO ₂ Snow" by Sherman et al., July/august 1991, pp 1970-1977 |
| | C02 | Journal of Vacuum Science & Technology A, "Carbon Dioxide Jet Spray Cleaning of Molecular Contaminants" by Hills, Jan/Feb. 1995, pgs.30-34 |
| | C03 | Particulate Science and Technology, Vol. 6, Number 2, 1988, "Methods for Surface Particle Removal: A Comparative Study" by Bardina |
| | C04 | "Trends in Wafer Cleaning Technology" by Hattori, May 1995, Contamination Control, Wafer Cleaning |
| | C05 | |

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.